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## BIB DATA SHEET

CONFIRMATION NO. 6541

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.		
10/528,069	07/10/2006	438	2893	122733		
<b>RULE</b>						
<b>APPLICANTS</b> Naoto Nakamura, Toyama, JAPAN; Iwao Nakamura, Toyama, JAPAN; Tomoharu Shimada, Nagasaki, JAPAN; Kenichi Ishiguro, Toyama, JAPAN; Sadao Nakashima, Toyama, JAPAN;						
<b>** CONTINUING DATA *****</b> This application is a 371 of PCT/JP03/12353 09/26/2003						
<b>** FOREIGN APPLICATIONS *****</b> JAPAN 2002-282231 09/27/2002 JAPAN 2003-051243 02/27/2003 JAPAN 2003-051244 02/27/2003						
<b>** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **</b> 05/17/2007						
Foreign Priority claimed <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No 35 USC 119(a-d) conditions met <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No Verified and /HOA B TRINH/ Acknowledged Examiner's Signature		<input type="checkbox"/> Met after Allowance Initials	<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWINGS</b> 11	<b>TOTAL CLAIMS</b> 18	<b>INDEPENDENT CLAIMS</b> 9
<b>ADDRESS</b> OLIFF & BERRIDGE, PLC P.O. BOX 320850 ALEXANDRIA, VA 22320-4850 UNITED STATES						
<b>TITLE</b> Thermal Treatment Apparatus, Method For Manufacturing Semiconductor Device, And Method For Manufacturing Substrate						
<b>FILING FEE RECEIVED</b> 2230	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:			<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit		